

# 光电子集成

## 晶圆级测试的内容、方法和技术挑战

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EXFO

# 关于EXFO

**95+**

of leading service  
providers  
using EXFO

**No.1**

in optical test  
solutions

**250+**

assurance  
systems deployed

**5000+**

Certification &  
Recognition

**40**

years of  
pioneering  
essential solutions  
and technologies

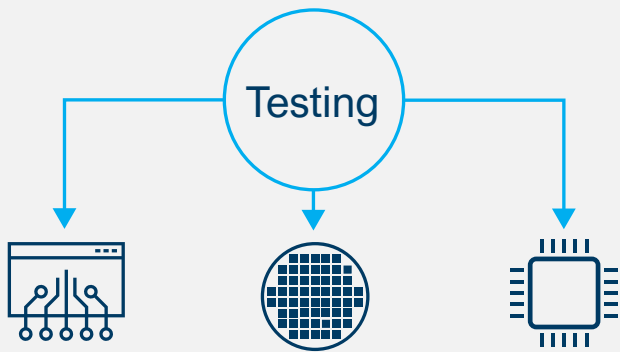
**1,900+**

employees in  
25 countries  
and customers  
in 120 countries

# 为什么PIC产业中测试非常重要？

1

Testing is required to validate & enhance PIC from wafer, die, assembly to module.



## Design

Wafer / Die

Full characterization  
Optical & Electrical

## Production

Wafer / Die

Find known  
good dies (KGD)

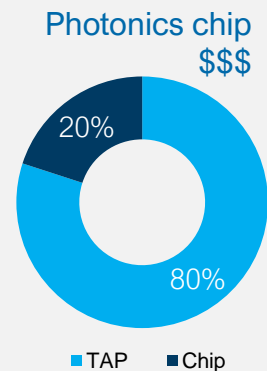
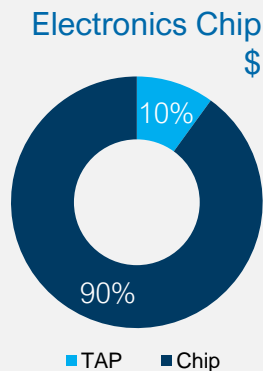
## Deployment

Assembly / Module

Final tests

2

**Known Good Dies (KGD)** are essential to make TAP (Testing, Assembly, Packaging) viable.

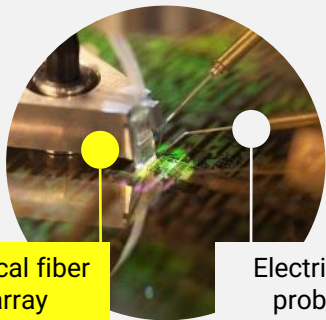


GOAL

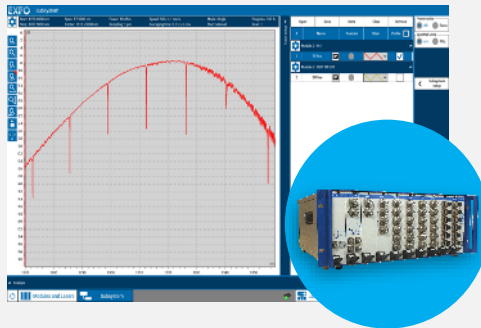
Efficient testing to find KGD

# PIC 晶圆级测试及挑战

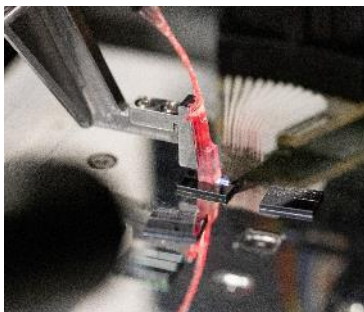
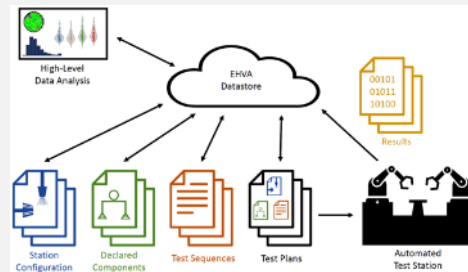
1 Optical coupling and electrical probing



2 Optical and electrical testing



3 Data management and analysis



## Bottlenecks



Accuracy and repeatability



Speed and efficiency



Data intelligence



Dealing with complexity



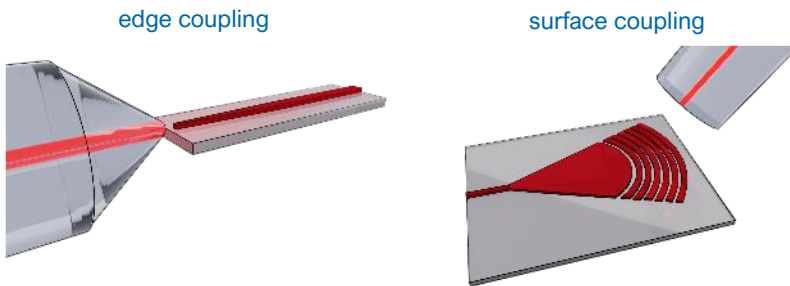
Flexibility / Scalability



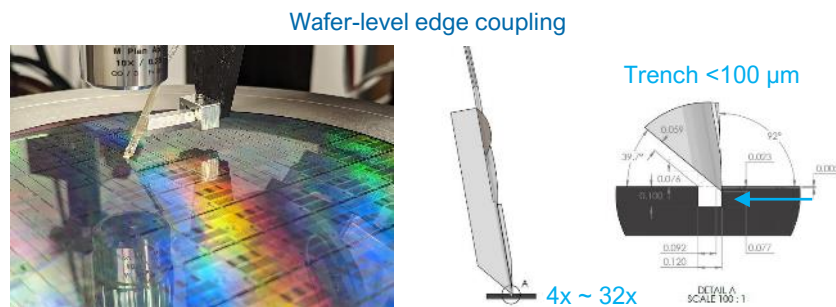
Ecosystem

# 光耦合与测试

PIC requires edge coupling  
for product performance and efficiency



Wafer-level edge coupling  
optimizing both accuracy and efficiency



## Edge coupling vs. surface coupling

- High coupling efficiency 1 dB or lower (vs.  $>3\text{dB}$ )
- Broad bandwidth 100 nm (vs. 30 nm)
- Low PDL  $\sim 0$  dB (vs. 1~3dB, more if TE/TM only)
- Needs cleaved facet, spot-size converter
- Challenging to probe at wafer-level

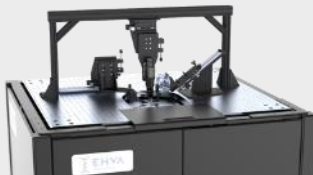
## OPAL-EC enables edge coupling on wafer

- Save time and cost versus singulated dies (separate dies, pick & place)
- Best accuracy and repeatability with low dependency in loss, bandwidth & PDL
- Multi-port for parallel testing, phase arrays & sensors

# 从晶圆至DIE的可升级探针测试台

CIOE Demo  
Booth 10B53

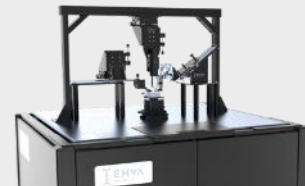
**OPAL EC**  
Wafer testing  
(up to Ø 300mm)



**OPAL MD**  
Multi-die testing  
(100x100 mm<sup>2</sup>)



**OPAL SD**  
Single-die testing  
(50x50 mm<sup>2</sup>)



**All form factors**

300mm wafer, bar,  
single & multiple  
dies

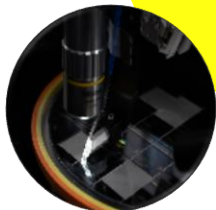
Stretch-tape

**Modular design**

Up to 4x Optical and  
Electrical probes  
Scalable SD, MD  
to EC

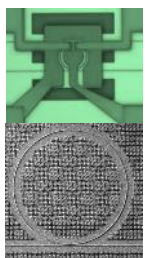
**Multi-port  
wafer-level  
edge coupling  
+ surface  
coupling**

**Automated  
stations with  
PIC dedicated  
software**

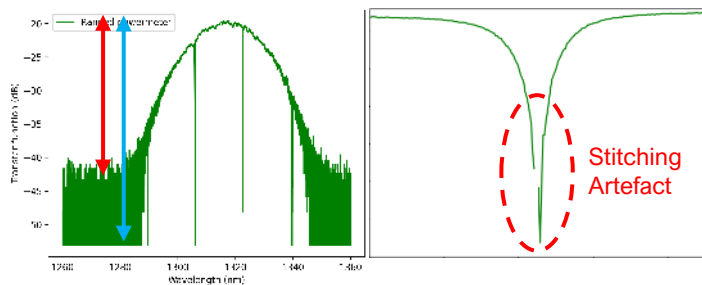


# 光测试挑战： 微腔（RING RESONATOR）测试（用例）

## High Q-factor Ring Resonators testing challenges



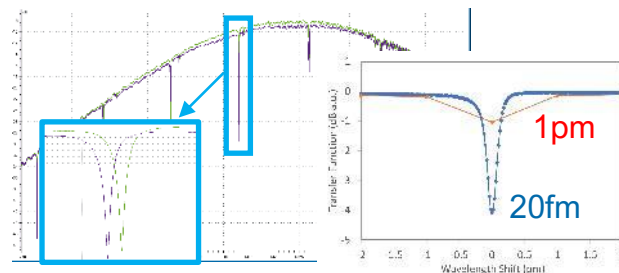
>1,000,000  
Q-factor



Limited dynamic range and resolution

- Wavelength range C+L bands
- High resolution, needing <math><0.1\text{pm}</math>
- Large power dynamic range >60dB
- Power contrast tracking 10dB/pm
- Speed and repeatability

## High-performance testing for Ring Resonators

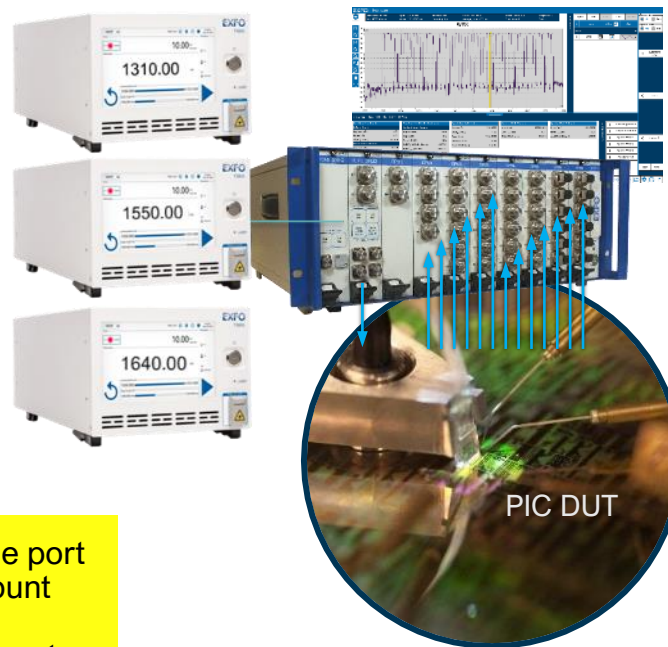
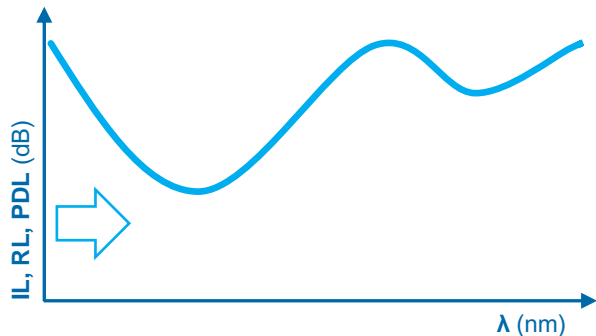


>70dB dynamic range and 20fm resolution

- Femtometer resolution 20fm
- >70dB dynamic range in a single scan
- 200 nm/s scan speed
- Slope tracking 10dB/pm, 100nm/s
- Support >6,000,000 Q-factor (future proof)



# 高性能器件测试平台 (CTP)



Full-band  
1240 nm ~  
1680 nm

Femtometer  
resolution  
20 fm

Dynamic  
range  
>70dB

Scan  
speed  
200 nm/s

Large port  
count  
96 ports

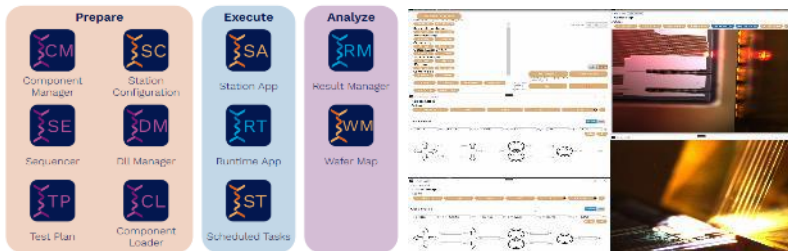
Combine all advanced testing capabilities within a single platform.



# 生产与批量测试

Wafer CAD files  
Chip parameters  
Test plans

## Single software platform



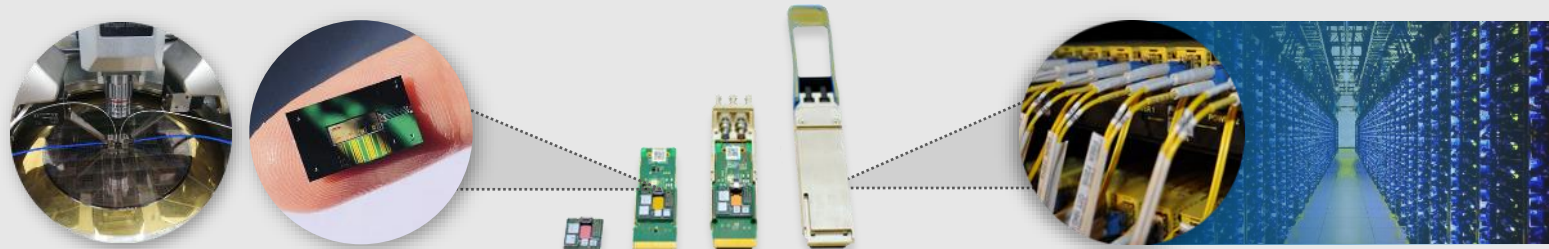
- PIC focused SW, multi-user single database
- Smart test plans, python script manager
- Automated from CAD file to analysis
- Flexible and scalable, EXFO or third-party
- Big data, AI / ML to reduce tests

## Integration Control Automation



# 更进一步 - PIC光收发器测试生态系统

Supports one PIC transceiver ecosystem, from Lab to Fab, Fab to Live



PIC testing



Optics and Module testing



Traffic and System testing

## 结论

01

AI is driving PIC from prototypes to production and the industry needs efficient testing to characterize and validate large batches of wafers.

02

Wafer-level edge-coupling and high-performance testing are critical to efficiently identify KGD and ensure quality starting from the wafer level.

03

A single software interface provides an automated flow from CAD files to analysis and offers scalability and flexibility to integrate different probes and instruments to support more complex and volume PIC testing.

04

AI and machine learning can be used to predict and skip bad circuits to optimize test time and save costs.

EXFO solutions support **the entire lifecycle** of new technology development and introduction **from lab-to-live.**

谢谢!

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